

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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| In re Application of: FORTIN et al. |) | |
| |) | |
| Serial No.: Not yet assigned |) | Examiner: Not yet assigned |
| |) | |
| Filing Date: Herewith |) | Group Art Unit: Not yet assigned |
| |) | |
| For: MICROELECTROMECHANICAL |) | Attorney Docket No.: 139641 |
| SYSTEM PRESSURE SENSOR AND |) | |
| METHOD FOR MAKING AND USING |) | |
| |) | |
| |) | |
| |) | |

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

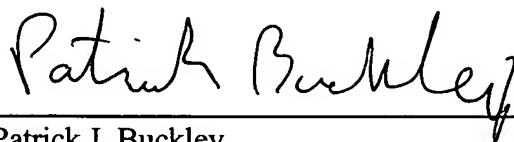
Applicants submit herewith patents, publications or other information of which they are aware that they believe may be material to the examination of this application, and in respect of which, there may be a duty to disclose.

The filing of this information disclosure statement shall not be construed as a representation that a thorough search has been made, an admission that the information cited is, or is considered to be, material to patentability, or that no other material information exists. Nor shall the filing of this information disclosure statement be construed as an admission against interest in any manner.

This Information Disclosure Statement is filed in accordance with 37 CFR §§1.56, 1.97 and 1.98. The items listed on the accompanying Form PTO-1449 may be deemed to be pertinent to the above-identified application and are made of record to assist the Patent and Trademark Office in its examination of this application. The Examiner is respectfully requested to fully consider the items listed on the enclosed copy of Form PTO-1449 and to independently ascertain their teaching.

No fee is believed to be due under 37 CFR §1.17(p) for this Information Disclosure Statement since it is being filed concurrently with the above-identified application.

Respectfully submitted,

A handwritten signature in cursive script, reading "Patrick Buckley", written over a horizontal line.

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March 12, 2004
Date

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|---|---|----|---|--------------------------|------------------|
| Substitute for form 1449A/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i> | | | | Complete if Known | |
| | | | | Application Number | not yet assigned |
| | | | | Filing Date | herewith |
| | | | | First Named Inventor | FORTIN et al. |
| | | | | Group Art Unit | not yet assigned |
| | | | | Examiner Name | not yet assigned |
| Sheet | 1 | of | 1 | Attorney Docket Number | 139641 |

| OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS | | | |
|---|-----------------------|---|----------------|
| Examiner Initials* | Cite No. ¹ | Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published. | T ² |
| | A | J.-S. PARK and Y.B. GIANCHANDANI, "A Low Cost Batch-Sealed Capacitive Pressure Sensor," IEEE No. 0-7803-5194-0 (1999) | |
| | B | A. V. CHAVAN and K. D. WISE, "A Monolithic Fully-Integrated Vacuum-Sealed CMOS Pressure Sensor," IEEE No. 0-7803-5273-4 (2000) | |
| | C | WEN H. KO and QIANG WANG, "Touch Mode Capacitive Pressure Sensors For Industrial Applications," IEEE No. 0-7803-3744-1 (1997) | |
| | D | HYEONCHEOL KIM and KUKJIN CHUN, "Integrated MEMS for Pressure Transponder," 1997 International Conference on Solid-State Sensors and Actuators, IEEE No. 0-7803-3829-4 (1997) | |
| | E | W. P. EATON and J. H. SMITH, "Micromachined Pressure Sensors: Review and Recent Developments," Smart Mater. Struct. 6, p 530-539 (1997) | |
| | F | ABHIJEET V. CHAVAN and KENSALL D. WISE, "A Monolithic Fully-Integrated Vacuum-Sealed CMOS Pressure Sensor," IEEE Transactions on Electron Devices, Vol. 49, No. 1 (January 2002) | |
| | G | C. HIEROLD et al., "Implantable Low Power Integrated Pressure Sensor System for Minimal Invasive Telemetric Patient Monitoring," IEEE No. 0-7803-4412-X (1999) | |
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|--------------------|--|-----------------|--|
| Examiner Signature | | Date Considered | |
|--------------------|--|-----------------|--|

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹Unique citation designation number. ²Applicant is to place a check mark here if English language Translation is attached.